

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent application of

Docket No. 6192.0091.D2

Woon-Yong PARK, *et al.*

Serial No.: Divisional of Application
Serial No. 09/968,522

Group Art Unit: TBD

Filed: Concurrently Herewith

Examiner: TBD

For: **PHOTOLITHOGRAPHY METHOD FOR THIN FILM (AS AMENDED)**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

Under the provisions of 37 C.F.R. 1.97 through 1.99 and pursuant to applicant's duty of disclosure under 37 C.F.R. 1.56, applicant respectfully brings the following documents, listed on the attached form PTO-1449, to the attention of the Examiner in charge of the above-identified application. The references cited in the attached PTO-1449 are readily available to the Examiner in co-pending parent U.S. Application Serial No: **09/968,522**. Thus, according to the rules of practice, these references are not provided herein, but are listed on the PTO-1449 form and should be considered by the Examiner. If the Examiner is unable to obtain the listed references, applicant will gladly provide such references upon notification by the Examiner in charge of the examination of the above-identified application.

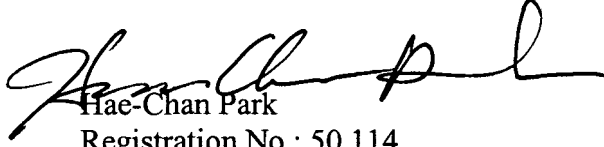
These citations do not constitute an admission that the references are relevant or material to the claims. They are only cited as constituting related art of which the applicant is aware.

It is respectfully requested that the listed references be considered by the Examiner and formally made of record in this application.

Please charge any deficiencies in fees and credit any overpayment of fees to Attorney's

Deposit Account No. 23-1951.

Respectfully submitted,


Hae-Chan Park
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Dated: July 28, 2003

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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not conformance and not considered. Include copy of this form with next communication to applicant.